1020020072380

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[Bibliography]

[Document Name]

Amendment to specification

[Receiver]

ادرچ

Commissioner

[Filing Date]

06 December 2002

[Applicant]

[Name]

Integrated Process Systems

[Applicant code]

1-1998-097346-8

[Relationship to the case]

Applicant

[Attorney]

[Name]

Youngpil Lee

[Attorney code]

9-1998-000334-6

[General Power of Attorney

Registration No.]

2002-030299-1

[Indication of the case]

[Application No.]

10-2002-0072380

[Application Date]

20 November 2002

[Date of Request for Examination] 20 November 2002

[Title]

Method for depositing thin film on wafer using Aluminum

compound

[Reason for submission]

[Receipt Number]

1-1-02-0383122-50

[Receipt Data]

20 November 2002

[Document to be amended]

Specification

[Items to be amended]

[Item subject to amendment] as attached

[Amendment method]

as attached

[Contact of amendment]

as attached

[Purpose]

We file as above according to Art. 13 of the Patent Law

Enforcement rule, and according to Art. 8 of the Utility Model

Law Enforcement rule.

Attorney

Youngpil Lee

[Fee]

[Amendment fee]

0 won

[Additional Examination fee] 0 won

[Other fees]

0 won

[Total]

0 won

[Enclosures]

1. Document certifying content of amendment

1 copy each